

**Notice of References Cited**

Application/Control No.

09/678,255

Applicant(s)/Patent Under  
Reexamination  
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Examiner

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Art Unit

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Page 1 of 1

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**NON-PATENT DOCUMENTS**

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	V	ORIEL Instruments, Optical Cleaning Supplies, <a href="http://www.oriel.com/netcat/Volumell/Descrpage/v3t6mat.htm">http://www.oriel.com/netcat/Volumell/Descrpage/v3t6mat.htm</a>
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	X	NASA Practice No. PD-ED-1233, Contamination Control Program

\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.